



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Application of Ying-Lang Wang, et al.

Confirmation No. 7230

Serial No.: 10/706,495

Examiner: Tuan H. Nguyen

Filed: November 12, 2003

Group Art Unit: 2813

For: CMP PROCESS LEAVING NO RESIDUAL OXIDE LAYER OR SLURRY

PARTICLES

Mail Stop Issue Fee Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 CERTIFICATE OF MAILING.

37 C.F.R. §1.8(a)

1 certify that this correspondence and the enclosures mentioned therein are being deposited by First Class U.S. Mail with sufficient postage on the date shown below, addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Richard A. Paikoff, Reg. No. 34,892

2 2 2 2 Date

AMENDMENT AFTER ALLOWANCE, 37 CFR § 1.312

Responsive to the Notice of Allowance and Fee(s) Due, dated December 1, 2004, Applicants respectfully request that the following corrections be made to the claims:

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claims 1 - 26 (cancelled)

Claim 27 (currently amended): A process for performing CMP, comprising: providing a dielectric layer having a first surface;